10/07/03

Please type a plus sign (+) inside this box → [+]

PTO/SB/08B (08-00)
Approved for use through 10/31/2002. OMB 0651-0031
U. S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE
Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449B/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 1 of 2

Complete if Known	
Application Number	10/680,592
Filing Date	07 October 2003 (herewith)
First Named Inventor	Christophe Pierrat
Group Art Unit	2825
Examiner Name	GARLOWSN
Attorney Docket Number	FTIS 1003-1

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.[1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T[2]
	C1	SMITH, TABER H., et al., "A CMP Model Combining Density and Time Dependencies," Proc. CMP-MIC, Santa Clara, CA Feb. 1999 8 pages	
	C2	STROLENBERG, CHRIS W., et al., "Stay Away from Minimum Design-Rule Values," ACM SIGDA CD-ROM Project, March 27-30, 2000, 2 pages	
	C3	GROBMAN, W., et al., "Reticle Enhancement Technology: Implications and Challenges for Physical Design," DAC 1001, June 18-22, 2001, Las Vegas, NV, 6 pages.	
	C4	GOLD, SPENCER M., et al., "A Quantitative Approach to Nonlinear Process Design Rule Scaling," Proceedings of Advanced Research in VLSI, March 21-24, 1999, pp. 99-112.	
	C5	DOONG, KELVIN Y., et al., "Scaling Variance, Invariance and Prediction of Design Rule: From 0.25-um to 0.10-um Nodes inthe Era of Foundry Manufacturing," IEEE, 2001, 38-42.	
	C6	CREPEAU, J., et al., "Some Results on Yield and Local Design Rule Relaxation," IEEE 1993, 144-151.	
	C7	TIAN, RUIQI, et al., "Model-Based Dummy Feature Placement for Oxide Chemical-Mechanical Polishing Manufacturability," DAC 2000, Los Angeles, CA 4 pages.	
	C8	RIEGER, MICHAEL L., et al., "Layout Design Methodologies for Sub-Wavelength Manufacturing," DAC 2001, June 18-22, 2001, Las Vegas, NV 4 pages.	
	C9	JEPPSON, KJELL O., et al., "Formal Definitions of Edge-Based Geometric Design Rules," IEEE Transactions on Computer-Aided Design of Integrated Circuits and Systems, 120(1) Jan. 1993, 59-69.	
	C10	Tu Wien, "An Introduction to the ASIC Technology and Design Flow," ICT Institute of Computer TEchnology, Feb 26, 2003, 29 pages.	
	C11	"MOSIS Scalable CMOS (SCMOS) Design Rules (Revision 8.0), MOSIS, Marina Del Rey, CA April 25, 2003, 51 pages.	

Examiner Signature		Date Considered	11/9/5

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

[1] Unique citation designation number. [2] Applicant is to place a check mark here if English language Translation is attached.

Burden Hour Statement: This form is estimated to take 2.0 hours to complete. Time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U. S. Patent and Trademark Office, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Assistant Commissioner for Patents, Washington, DC 20231.

Please type a plus sign (+) inside this box → [+]

PTO/SB/08B (08-00)
Approved for use through 10/31/2002. OMB 0651-0031
U. S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449B/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 2 of 2

Complete If Known	
Application Number	10/690,592
Filing Date	07 October 2003 (herewith)
First Named Inventor	Christophe Pierrat
Group Art Unit	2825
Examiner Name	GARROUSSU
Attorney Docket Number	FTIS 1003-1

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.[1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T[2]
KP	C12	FRERICHS, M.R., "Precise Extraction of Ultra Deep Submicron Interconnect Parasitics with Parameterized 3D-Modeling," Proceedings of the 2001 conference on Asia South Pacific design automation, Yokohama, Japan, 50 - 56.	
KP	C13	SCHELLENBERG, F.M., et al., "Adoption of OPC and the Impact on Design and Layout," DAC 2001, June 18-22, 2001, Las Vegas, NV, 4 pages	
	C14		

Examiner Signature		Date Considered	11/9/5

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

[1] Unique citation designation number. [2] Applicant is to place a check mark here if English language Translation is attached.

Burden Hour Statement: This form is estimated to take 2.0 hours to complete. Time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U. S. Patent and Trademark Office, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Assistant Commissioner for Patents, Washington, DC 20231.

PTO/SB/08A (10-01)
Approved for use through 10/31/2002. OMB 0651-0031
U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE
Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

SEP 06 2005
PATENT & TRADEMARK OFFICE

	1	of	2

Complete if Known	
Application No.	10/680,592
Filing Date	October 7, 2003
First Named Inventor	Christophe Pierrat
Art Unit	2825
Examiner Name	~~Not Yet Known~~ GARBOWSKI
Attorney Docket Number	23748-10030

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.[1]	Document No. Number – Kind Code[2] (if known)	Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		US-		

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No.[1]	Foreign Patent Document: Country Code[3] – Number[4] Kind Code[5] (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	T[6]

OTHER REFERENCES – NON-PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.[1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T[6]
WS	C1	CREPEAU, J. et al., "Some Results on Yield and Local Design Rule Relaxation," IEEE 1993, 144-151.	
WS	C2	DOONG, Kelvin Y. et al., "Scaling Variance, Invariance and Prediction of Design Rule: From 0.25-um to 0.10-um Nodes in the Era of Foundry Manufacturing," IEEE, 2001, 38-42.	
WS	C3	GOLD, Spencer M. et al., "A Quantitative Approach fo Nonlinear Process Design Rule Scaling," Proceedings of Advanced Research in VLSI, March 21-24, 1999, pp. 99-112.	
WS	C4	GROBMAN, W. et al., "Reticle Enhancement Technology: Implications and Challenges for Physical Design," DAC 1001, June 18-22, 2001, Las Vegas, NV, 6 pages.	
WS	C5	JEPPSON, Kjell O. et al., "Formal Definitions of Edge-Baed Geometric Design Rules," IEEE Transactions on Computer-Aided Design of Integrated Circuits and Systems, 120(1) Jan. 1993, 56-59.	
WS	C6	RIEGER, Michael L. et al., "Layout Design Methodologies for Sub-Wavelength Manufacturing," DAC 2001, June 18-22, 2001, Las Vegas, NV, 4 pages.	
WS	C7	SMITH, Taber H. et al., "A CMP Model Combining Density and Time Dependencies," Proc. CMP-MIC, Santa Clara, CA, Feb. 1999, 8 pages.	
WS	C8	STROLENBERG, Chris W. et al., "Stay Away from Minimum Design-Rule Values," ACM SIGDA CD-ROM Project, March 27-30, 2000, 2 pages.	
WS	C9	TIAN, Ruiqi et al., "Model-Based Dummy Feature Placement for Oxide Chemical-Mechanical Polishing Manufacturability," DAC 2000, Los Angeles, CA, 4 pages.	

Examiner Signature		Date Considered	11/9/05

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609.
Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

[1]Applicant's unique citation designation number (optional). [2]See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. [3]Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). [4]For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. [5]Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. [6]Applicant is to place a check mark here if English language Translation is attached.

PTO/SB/08A (10-01)
Approved for use through 10/31/2002. OMB 0651-0031
U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE
Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

	2	of	2

	Complete if Known
Application No.	10/680,592
Filing Date	October 7, 2003
First Named Inventor	Christophe Pierrat
Art Unit	2825
Examiner Name	~~Not Yet Known~~ GARBOWSKI
Attorney Docket Number	23748-10030

OTHER REFERENCES – NON-PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.[1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T[6]
WD	C10	WIEN, Tu, "An Introduction to the ASIC Technology and Design Flow," ICT Institute of Computer Technology, Feb. 26, 2003, 29 pages.	

Examiner Signature		Date Considered	11/9/05

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609.
Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

[1]Applicant's unique citation designation number (optional). [2]See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. [3]Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). [4]For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. [5]Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. [6]Applicant is to place a check mark here if English language Translation is attached.

OIPE
OCT 17 2005
IAP19
PATENT & TRADEMARK OFFICE

PTO/SB/08A (10-01)
Approved for use through 10/31/2002. OMB 0651-0031
U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE
Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Complete if Known	
Application No.	10/680,592
Filing Date	October 7, 2003
First Named Inventor	Christophe Pierrat
Art Unit	2825
Examiner Name	~~Not Yet Known~~ GARBOWSKI
Attorney Docket Number	23748-10030

Sheet 1 of 1

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.[1]	Document No. Number – Kind Code[2] (if known)	Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		US-		
		US-		

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No.[1]	Foreign Patent Document Country Code[3] – Number[4] Kind Code[5] (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	T[6]

OTHER REFERENCES – NON-PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.[1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T[6]
WS	C1	Chemical Mechanical Polishing (CMP), date unknown, 13 pages.	
WD	C2	WOODIE, D., Chemical Mechanical Polishing Primer, Cornell Nanfoabrication Facility, date unknown, 14 pages.	

Examiner Signature		Date Considered	11/9/5

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609.
Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

[1]Applicant's unique citation designation number (optional). [2]See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. [3]Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). [4]For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. [5]Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. [6]Applicant is to place a check mark here if English language Translation is attached.